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Substitute for form 1449A/PTO			Complete if Known		
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (use as many sheets as necessary)			Application Number	09/954,864	
			Filing Date	9/17/01	
			First Named Inventor	Patel	
			Art Unit	1763	
			Examiner Name	Olsen, Allan	
Sheet	1	of	6	Attorney Docket Number	P68-US

U.S. PATENT DOCUMENTS					
Examiner Initials ¹	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number - Kind Code ² (if known)			
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Examiner Signature	<i>Alla Olsen</i>	Date Considered	3/7/05
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		Filing Date	9/17/01
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		Art Unit	1763
		Examiner Name	Olsen, Allan
Sheet	2	of	6
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Examiner Signature	<i>Allan Olsen</i>	Date Considered	3-7-05
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			Application Number	09/954,864	
Sheet	4	of	6	Filing Date	9/17/01
			First Named Inventor	Patel	
			Group Art Unit	1763	
			Examiner Name	Olsen, Allan	
			Attorney Docket Number	P68-US	

OTHER PRIOR ART – NON PATENT LITERATURE DOCUMENTS			
Examiner Initials ¹	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
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